

## ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18

Stylesheet Version v18.0

### Title of Invention

HIGH PRESSURE PROCESSING CHAMBER FOR A  
SEMICONDUCTOR WAFER

Application Number : 10/680783  
Confirmation Number: 5859  
First Named Applicant: William Jones  
Attorney Docket Number:  
Art Unit:  
Examiner:  
Search string: ( 6264752 ).pn



Certification: This Information Disclosure Statement was submitted under the following conditions, which satisfies the requirement under 37 CFR 1.97(e). The filer certified:

That each item of information contained in the information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of the information disclosure statement.

### US Patent Documents

**Note: Applicant is not required to submit a paper copy of cited US Patent Documents**

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
	1	6264752	2001-07-24	Curtis et al.			

### Signature

Examiner Name	Date